Dzung Viet Dao

List of Publications by Citations

263 papers	3,759 citations	33 h-index	46 g-index
324 ext. papers	4,672 ext. citations	4 avg, IF	5.85 L-index

#	Paper	IF	Citations
263	The Piezoresistive Effect of SiC for MEMS Sensors at High Temperatures: A Review. *Journal of Microelectromechanical Systems*, **2015**, 24, 1663-1677	2.5	150
262	Environment-friendly carbon nanotube based flexible electronics for noninvasive and wearable healthcare. *Journal of Materials Chemistry C*, **2016**, 4, 10061-10068	7.1	90
261	Natural fiber□einforced composites: A review on material, manufacturing, and machinability. *Journal of Thermoplastic Composite Materials*, **2021**, 34, 238-284	1.9	86
260	Graphite on paper as material for sensitive thermoresistive sensors. *Journal of Materials Chemistry C*, **2015**, 3, 8776-8779	7.1	80
259	. *Journal of Microelectromechanical Systems*, **2017**, 26, 966-986	2.5	78
258	Long-Lived, Transferred Crystalline Silicon Carbide Nanomembranes for Implantable Flexible Electronics. *ACS Nano*, **2019**, 13, 11572-11581	16.7	65
257	Integrated photonic platform for quantum information with continuous variables. *Science Advances* , **2018**, 4, eaat9331	14.3	60
256	Fundamental piezoresistive coefficients of p-type single crystalline 3C-SiC. *Applied Physics Letters*, **2014**, 104, 111905	3.4	59
255	Stretchable respiration sensors: Advanced designs and multifunctional platforms for wearable physiological monitoring. *Biosensors and Bioelectronics*, **2020**, 166, 112460	11.8	59
254	Digital polymerase chain reaction technology - recent advances and future perspectives. *Lab on A Chip*, **2018**, 18, 3717-3732	7.2	59
253	Development of miniaturized 6-axis accelerometer utilizing piezoresistive sensing elements. *Sensors and Actuators A: Physical*, **2007**, 134, 310-320	3.9	55
252	Development and Analysis of a Sliding Tactile Soft Fingertip Embedded With a Microforce/Moment Sensor. *IEEE Transactions on Robotics*, **2011**, 27, 411-424	6.5	48
251	Ultrahigh-sensitive WO3 nanosensor with interdigitated Au nano-electrode for NO2 detection. *Sensors and Actuators B: Chemical*, **2008**, 132, 234-238	8.5	48
250	Piezoresistive effect in p-type 3C-SiC at high temperatures characterized using Joule heating. *Scientific Reports*, **2016**, 6, 28499	4.9	47
249	Thickness dependence of the piezoresistive effect in p-type single crystalline 3C-SiC nanothin films. *Journal of Materials Chemistry C*, **2014**, 2, 7176-7179	7.1	47
248	Development of a dual-axis thermal convective gas gyroscope. *Journal of Micromechanics and Microengineering*, **2006**, 16, 1301-1306	2	46
247	A survey of practical equations for prediction of effective thermal conductivity of spherical-particle nanofluids. *Journal of Molecular Liquids*, **2015**, 211, 712-733	6	45

246	Investigation of strain sensing effect in modified single-defect photonic crystal nanocavity. *Optics Express*, **2011**, 19, 8821-9	3.3	43
245	Piezoresistive Effect of p-Type Single Crystalline 3C-SiC Thin Film. *IEEE Electron Device Letters*, **2014**, 35, 399-401	4.4	42
244	The Piezoresistive Effect in Top-Down Fabricated p-Type 3C-SiC Nanowires. *IEEE Electron Device Letters*, **2016**, 37, 1029-1032	4.4	41
243	Single-Crystalline 3C-SiC anodically Bonded onto Glass: An Excellent Platform for High-Temperature Electronics and Bioapplications. *ACS Applied Materials & Interfaces*, **2017**, 9, 27365-27371	8.5	41
242	Charge transport and activation energy of amorphous silicon carbide thin film on quartz at elevated temperature. *Applied Physics Express*, **2015**, 8, 061303	2.4	40
241	Thermal Flow Sensors for Harsh Environments. *Sensors*, **2017**, 17,	3.8	40
240	Deformation of a floating liquid marble. *Soft Matter*, **2015**, 11, 4576-83	3.6	40
239	Solvent-free fabrication of biodegradable hot-film flow sensor for noninvasive respiratory monitoring. *Journal Physics D: Applied Physics*, **2017**, 50, 215401	3	39
238	Highly sensitive 4H-SiC pressure sensor at cryogenic and elevated temperatures. *Materials and Design*, **2018**, 156, 441-445	8.1	39
237	Development of PZT Actuated Valveless Micropump. *Sensors*, **2018**, 18,	3.8	37
236	Floating mechanism of a small liquid marble. *Scientific Reports*, **2016**, 6, 21777	4.9	36
235	Active demultiplexing of single photons from a solid-state source. *Laser and Photonics Reviews*, **2017**, 11, 1600297	8.3	35
234	Fabrication and analysis of high-performance piezoelectric MEMS generators. *Journal of Micromechanics and Microengineering*, **2012**, 22, 065017	2	35
233	Piezoresistive effect of p-type silicon nanowires fabricated by a top-down process using FIB implantation and wet etching. *RSC Advances*, **2015**, 5, 82121-82126	3.7	34
232	Experimental Investigation of Piezoresistive Effect in p-Type 4H-SiC. *IEEE Electron Device Letters*, **2017**, 38, 955-958	4.4	33
231	Coalescence Processes of Droplets and Liquid Marbles. *Micromachines*, **2017**, 8,	3.3	33
230	Nano strain-amplifier: Making ultra-sensitive piezoresistance in nanowires possible without the need of quantum and surface charge effects. *Applied Physics Letters*, **2016**, 109, 123502	3.4	33
229	Evaporation of Ethanol-Water Binary Mixture Sessile Liquid Marbles. *Langmuir*, **2016**, 32, 6097-104	4	33

228	Piezoresistive effect of p-type single crystalline 3C-SiC on (111) plane. *RSC Advances*, **2016**, 6, 21302-21307	3.7	31
227	Liquid marbles as biochemical reactors for the polymerase chain reaction. *Lab on A Chip*, **2019**, 19, 3220-3227	7.2	31
226	Thermoresistive properties of p-type 3C-SiC nanoscale thin films for high-temperature MEMS thermal-based sensors. *RSC Advances*, **2015**, 5, 106083-106086	3.7	31
225	Liquid marble coalescence via vertical collision. *Soft Matter*, **2018**, 14, 4160-4168	3.6	30
224	Evaporation dynamics of liquid marbles at elevated temperatures.. *RSC Advances*, **2018**, 8, 15436-15443	3.7	30
223	Highly sensitive pressure sensors employing 3C-SiC nanowires fabricated on a free standing structure. *Materials and Design*, **2018**, 156, 16-21	8.1	30
222	Excellent Rectifying Properties of the n-3C-SiC/p-Si Heterojunction Subjected to High Temperature Annealing for Electronics, MEMS, and LED Applications. *Scientific Reports*, **2017**, 7, 17734	4.9	30
221	Giant piezoresistive effect by optoelectronic coupling in a heterojunction. *Nature Communications*, **2019**, 10, 4139	17.4	28
220	3C-SiC/Si Heterostructure: An Excellent Platform for Position-Sensitive Detectors Based on Photovoltaic Effect. *ACS Applied Materials & Interfaces*, **2019**, 11, 40980-40987	9.5	28
219	A 2-DOF convective micro accelerometer with a low thermal stress sensing element. *Smart Materials and Structures*, **2007**, 16, 2308-2314	3.4	28
218	The effect of strain on the electrical conductance of p-type nanocrystalline silicon carbide thin films. *Journal of Materials Chemistry C*, **2015**, 3, 1172-1176	7.1	27
217	Electrical Properties of p-type 3C-SiC/Si Heterojunction Diode Under Mechanical Stress. *IEEE Electron Device Letters*, **2014**, 35, 1293-1295	4.4	27
216	Micro/nano-mechanical sensors and actuators based on SOI-MEMS technology. *Journal of Family Business Management*, **2010**, 1, 013001	2.2	27
215	An On-Chip SiC MEMS Device with Integrated Heating, Sensing, and Microfluidic Cooling Systems. *Advanced Materials Interfaces*, **2018**, 5, 1800764	4.6	26
214	Development of a Dual-Axis Convective Gyroscope With Low Thermal-Induced Stress Sensing Element. *Journal of Microelectromechanical Systems*, **2007**, 16, 950-958	2.5	26
213	High thermosensitivity of silicon nanowires induced by amorphization. *Materials Letters*, **2016**, 177, 80-84	3.3	26
212	Core-Shell Beads Made by Composite Liquid Marble Technology as A Versatile Microreactor for Polymerase Chain Reaction. *Micromachines*, **2020**, 11,	3.3	25
211	Self-Powered Broadband (UV-NIR) Photodetector Based on 3C-SiC/Si Heterojunction. *IEEE Transactions on Electron Devices*, **2019**, 66, 1804-1809	2.9	24

210	Orientation dependence of the pseudo-Hall effect in p-type 3C-SiC four-terminal devices under mechanical stress. *RSC Advances*, **2015**, 5, 56377-56381	3.7	24
209	Fabrication and Basic Characterization of a Piezoelectric Valveless Micro Jet Pump. *Japanese Journal of Applied Physics*, **2008**, 47, 8615-8618	1.4	24
208	Flexible and multifunctional electronics fabricated by a solvent-free and user-friendly method. *RSC Advances*, **2016**, 6, 77267-77274	3.7	24
207	The effect of device geometry and crystal orientation on the stress-dependent offset voltage of 3C-SiC(100) four terminal devices. *Journal of Materials Chemistry C*, **2015**, 3, 8804-8809	7.1	23
206	The Dependence of Offset Voltage in p-Type 3C-SiC van der Pauw Device on Applied Strain. *IEEE Electron Device Letters*, **2015**, 36, 708-710	4.4	23
205	Design and fabrication of a miniaturized six-degree-of-freedom piezoresistive accelerometer. *Journal of Micromechanics and Microengineering*, **2005**, 15, 1745-1753	2	23
204	Dielectrophoretic Trapping of a Floating Liquid Marble. *Physical Review Applied*, **2019**, 11,	4.3	22
203	Advances in Rational Design and Materials of High-Performance Stretchable Electromechanical Sensors. *Small*, **2020**, 16, e1905707	11	22
202	Highly sensitive 3C-SiC on glass based thermal flow sensor realized using MEMS technology. *Sensors and Actuators A: Physical*, **2018**, 279, 293-305	3.9	22
201	Pushing the Limits of Piezoresistive Effect by Optomechanical Coupling in 3C-SiC/Si Heterostructure. *ACS Applied Materials & Interfaces*, **2017**, 9, 39921-39925	9.5	22
200	Fabrication and testing of polymer cantilevers for VOC sensors. *Sensors and Actuators A: Physical*, **2013**, 202, 233-239	3.9	21
199	Micromachined NH3 Gas Sensor with ppb-level Sensitivity Based on WO3 Nanoparticles Thinfilm. *Procedia Engineering*, **2011**, 25, 1149-1152		21
198	Simulation, fabrication and characterization of a three-axis piezoresistive accelerometer. *Smart Materials and Structures*, **2006**, 15, 1691-1699	3.4	21
197	High-temperature tolerance of the piezoresistive effect in p-4H-SiC for harsh environment sensing. *Journal of Materials Chemistry C*, **2018**, 6, 8613-8617	7.1	20
196	Integration of SWNT film into MEMS for a micro-thermoelectric device. *Smart Materials and Structures*, **2010**, 19, 075003	3.4	20
195	Versatile microfluidic total internal reflection (TIR)-based devices: application to microbeads velocity measurement and single molecule detection with upright and inverted microscope. *Lab on A Chip*, **2009**, 9, 244-50	7.2	20
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193	Hydrogen sensor based on palladium-yttrium alloy nanosheet. *Materials Chemistry and Physics*, **2017**, 194, 231-235	4.4	19

192	Isotropic piezoresistance of p-type 4H-SiC in (0001) plane. *Applied Physics Letters*, **2018**, 113, 012104	3.4	19
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190	Paper-Based Electronics Using Graphite and Silver Nanoparticles for Respiration Monitoring. *IEEE Sensors Journal*, **2019**, 19, 11784-11790	4	18
189	Robust Free-Standing Nano-Thin SiC Membranes Enable Direct Photolithography for MEMS Sensing Applications. *Advanced Engineering Materials*, **2018**, 20, 1700858	3.5	18
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186	Ultra-high strain in epitaxial silicon carbide nanostructures utilizing residual stress amplification. *Applied Physics Letters*, **2017**, 110, 141906	3.4	17
185	RF MEMS switches for smart antennas. *Microsystem Technologies*, **2015**, 21, 487-495	1.7	17
184	Unintentionally Doped Epitaxial 3C-SiC(111) Nanothin Film as Material for Highly Sensitive Thermal Sensors at High Temperatures. *IEEE Electron Device Letters*, **2018**, 39, 580-583	4.4	17
183	Simulation and Fabrication of a Convective Gyroscope. *IEEE Sensors Journal*, **2008**, 8, 1530-1538	4	17
182	Straight movement of micro containers based on ratchet mechanisms and electrostatic comb-drive actuators. *Journal of Micromechanics and Microengineering*, **2006**, 16, 2532-2538	2	17
181	Pseudo-Hall effect in single crystal 3C-SiC(111) four-terminal devices. *Journal of Materials Chemistry C*, **2015**, 3, 12394-12398	7.1	16
180	Advances in electrode and electrolyte improvements in vanadium redox flow batteries with a focus on the nanofluidic electrolyte approach. *Physics Reports*, **2020**, 881, 1-49	27.7	16
179	Onset of thermomagnetic convection around a vertically oriented hot-wire in ferrofluid. *Journal of Magnetism and Magnetic Materials*, **2018**, 456, 300-306	2.8	15
178	Highly sensitive p-type 4H-SiC van der Pauw sensor.. *RSC Advances*, **2018**, 8, 3009-3013	3.7	15
177	High Power and Reliable SPST/SP3T RF MEMS Switches for Wireless Applications. *IEEE Electron Device Letters*, **2016**, 37, 1219-1222	4.4	15
176	Design and Simulation of a Novel 3-DOF MEMS Convective Gyroscope. *IEEJ Transactions on Sensors and Micromachines*, **2008**, 128, 219-224	0.2	15
175	Fabrication and Characterization of Smooth Si Mold for Hot Embossing Process. *IEEJ Transactions on Sensors and Micromachines*, **2007**, 127, 187-191	0.2	15

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173	Design, simulation and fabrication of a total internal reflection (TIR)-based chip for highly sensitive fluorescent imaging. *Journal of Micromechanics and Microengineering*, **2007**, 17, 1139-1146	2	14
172	A micro transportation system (MTS) with large movement of containers driven by electrostatic comb-drive actuators. *Journal of Micromechanics and Microengineering*, **2007**, 17, 2125-2131	2	14
171	Critical Trapping Conditions for Floating Liquid Marbles. *Physical Review Applied*, **2020**, 13,	4.3	14
170	Accurate dielectrophoretic positioning of a floating liquid marble with a two-electrode configuration. *Microfluidics and Nanofluidics*, **2019**, 23, 1	2.8	13
169	An automated on-demand liquid marble generator based on electrohydrodynamic pulling. *Review of Scientific Instruments*, **2019**, 90, 055102	1.7	13
168	Superior Robust Ultrathin Single-Crystalline Silicon Carbide Membrane as a Versatile Platform for Biological Applications. *ACS Applied Materials & Interfaces*, **2017**, 9, 41641-41647	9.5	13
167	Electrically Stable Carbon Nanotube Yarn Under Tensile Strain. *IEEE Electron Device Letters*, **2017**, 38, 1331-1334	4.4	13
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161	Electrical Resistance of Carbon Nanotube Yarns Under Compressive Transverse Pressure. *IEEE Electron Device Letters*, **2018**, 39, 584-587	4.4	12
160	Piezoelectric MEMS low-level vibration energy harvester with PMN-PT single crystal cantilever. *Electronics Letters*, **2012**, 48, 784	1.1	12
159	3C-SiC on glass: an ideal platform for temperature sensors under visible light illumination. *RSC Advances*, **2016**, 6, 87124-87127	3.7	12
158	Numerical simulation of combined natural and thermomagnetic convection around a current carrying wire in ferrofluid. *Journal of Magnetism and Magnetic Materials*, **2019**, 489, 165383	2.8	11
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155	Self-powered monolithic accelerometer using a photonic gate. *Nano Energy*, **2020**, 76, 104950	17.1	11
154	A hot-film air flow sensor for elevated temperatures. *Review of Scientific Instruments*, **2019**, 90, 015007	1.7	10
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151	A micromirror with CNTs hinge fabricated by the integration of CNTs film into a MEMS actuator. *Journal of Micromechanics and Microengineering*, **2013**, 23, 075024	2	10
150	Ultra-sensitive self-powered position-sensitive detector based on horizontally-aligned double 3C-SiC/Si heterostructures. *Nano Energy*, **2021**, 79, 105494	17.1	10
149	Steady-state analytical model of suspended p-type 3C-SiC bridges under consideration of Joule heating. *Journal of Micromechanics and Microengineering*, **2017**, 27, 075008	2	9
148	Influence of external mechanical stress on electrical properties of single-crystal n-3C-SiC/p-Si heterojunction diode. *Applied Physics Express*, **2015**, 8, 061302	2.4	9
147	Optothermotronic effect as an ultrasensitive thermal sensing technology for solid-state electronics. *Science Advances*, **2020**, 6, eaay2671	14.3	9
146	Piezo-Hall effect in single crystal p-type 3C-SiC(100) thin film grown by low pressure chemical vapor deposition. *RSC Advances*, **2016**, 6, 31191-31195	3.7	9
145	Multimodule Micro Transportation System Based on Electrostatic Comb-Drive Actuator and Ratchet Mechanism. *Journal of Microelectromechanical Systems*, **2011**, 20, 140-149	2.5	9
144	Novel fabrication process for a monolithic PMMA torsion mirror and vertical comb actuator. *Journal of Micromechanics and Microengineering*, **2011**, 21, 065032	2	9
143	Drilling Behavior of Flax/Poly(Lactic Acid) Bio-Composite Laminates: An Experimental Investigation. *Journal of Natural Fibers*, **2020**, 17, 1264-1280	1.8	9
142	Advances in ultrasensitive piezoresistive sensors: from conventional to flexible and stretchable applications. *Materials Horizons*, **2021**, 8, 2123-2150	14.4	9
141	Low-Cost Graphite on Paper Pressure Sensor for a Robot Gripper with a Trivial Fabrication Process. *Sensors*, **2018**, 18,	3.8	9
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138	Graphite-on-paper based tactile sensors using plastic laminating technique **2015**,		8
137	Micromachined Coreless Single-Layer Transformer Without Crossovers. *IEEE Magnetics Letters*, **2015**, 6, 1-4	1.6	8
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134	Pressure and temperature sensitive e-skin for in situ robotic applications. *Materials and Design*, **2021**, 208, 109886	8.1	8
133	Thermoresistance of p-Type 4H□SiC Integrated MEMS Devices for High-Temperature Sensing. *Advanced Engineering Materials*, **2019**, 21, 1801049	3.5	7
132	Development of polymer electrostatic comb-drive actuator using hot embossing and ultraprecision cutting technology. *Journal of Micro/ Nanolithography, MEMS, and MOEMS*, **2009**, 8, 043065	0.7	7
131	Development of polymer MEMS process technology as an approach to a sustainable production system. *Advances in Natural Sciences: Nanoscience and Nanotechnology*, **2012**, 3, 015009	1.6	7
130	A Fully Integrated MEMS-Based Convective 3-DOF Gyroscope **2007**,		7
129	A new structure of Tesla coupled nozzle in synthetic jet micro-pump. *Sensors and Actuators A: Physical*, **2020**, 315, 112296	3.9	7
128	A Generalized Analytical Model for Joule Heating of Segmented Wires. *Journal of Heat Transfer*, **2018**, 140,	1.8	6
127	Characterization of the piezoresistance in highly doped p-type 3C-SiC at cryogenic temperatures.. *RSC Advances*, **2018**, 8, 29976-29979	3.7	6
126	Fabrication and Characterization of 3-DOF Soft-Contact Tactile Sensor Utilizing 3-DOF Micro Force Moment Sensor. *IEEJ Transactions on Sensors and Micromachines*, **2007**, 127, 177-181	0.2	6
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121	Study on contact resistance in single-contact and multi-contact MEMS switches. *Microelectronic Engineering*, **2015**, 135, 13-16	2.5	5

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119	Charge reduced nanoparticles by sub-kHz ac electrohydrodynamic atomization toward drug delivery applications. *Applied Physics Letters*, **2020**, 116, 023703	3.4	5
118	A rapid and cost-effective metallization technique for 3C-SiC MEMS using direct wire bonding.. *RSC Advances*, **2018**, 8, 15310-15314	3.7	5
117	Towards highly sensitive strain sensing based on nanostructured materials. *Advances in Natural Sciences: Nanoscience and Nanotechnology*, **2010**, 1, 045012	1.6	5
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115	Piezoresistive effect in silicon nanowires A comprehensive analysis based on first-principles calculations **2009**,		5
114	Ultra miniature novel three-axis micro accelerometer **2009**,		5
113	Evaluation of the piezoresistive effect in single crystalline silicon nanowires **2009**,		5
112	Convective Gas Gyroscope Based on Thermo-Resistive Effect in Si P-N Junction **2007**,		5
111	A dual axis thermal convective silicon gyroscope		5
110	A Wearable, Bending-Insensitive Respiration Sensor Using Highly Oriented Carbon Nanotube Film. *IEEE Sensors Journal*, **2021**, 21, 7308-7315	4	5
109	Soft ionic liquid multi-point touch sensor.. *RSC Advances*, **2019**, 9, 10733-10738	3.7	4
108	Highly-doped SiC resonator with ultra-large tuning frequency range by Joule heating effect. *Materials and Design*, **2020**, 194, 108922	8.1	4
107	Lithography and Etching-Free Microfabrication of Silicon Carbide on Insulator Using Direct UV Laser Ablation . *Advanced Engineering Materials*, **2020**, 22, 1901173	3.5	4
106	Design and analysis of a z-axis tuning fork gyroscope with guided-mechanical coupling. *Microsystem Technologies*, **2014**, 20, 281-289	1.7	4
105	A micro gearing system based on a ratchet mechanism and electrostatic actuation. *Microsystem Technologies*, **2013**, 19, 261-267	1.7	4
104	Fabrication of optically smooth, through-wafer silicon molds for PDMS total internal reflection-based devices. *Microsystem Technologies*, **2009**, 15, 1845-1853	1.7	4
103	Single mask, simple structure micro rotational motor driven by electrostatic comb-drive actuators. *Journal of Micromechanics and Microengineering*, **2012**, 22, 015008	2	4

102	Optimum design considerations for a 3-DOF micro accelerometer using nanoscale piezoresistors **2008**,		4
101	Development of a 3-DOF Micro Accelerometer with Wireless Readout. *IEEJ Transactions on Sensors and Micromachines*, **2008**, 128, 235-239	0.2	4
100	Design and Fabrication of Polymer Electrostatic Comb-Drive Actuators for Micro Conveyer Systems. *IEEJ Transactions on Sensors and Micromachines*, **2006**, 126, 306-311	0.2	4
99	A MEMS-based microsensor to measure all six components of force and moment on a near-wall particle in turbulent flow		4
98	Advances in Si and SiC Materials for High-Performance Supercapacitors toward Integrated Energy Storage Systems. *Small*, **2021**, 17, e2101775	11	4
97	Strain Effect in Highly-Doped n-Type 3C-SiC-on-Glass Substrate for Mechanical Sensors and Mobility Enhancement. *Physica Status Solidi (A) Applications and Materials Science*, **2018**, 215, 1800288	1.6	4
96	Biosensors and Chemical Sensors for Healthcare Monitoring: A Review. *IEEJ Transactions on Electrical and Electronic Engineering*, **2022**, 17, 626-636	1	4
95	Enhanced Electrohydrodynamics for Electrospinning a Highly Sensitive Flexible Fiber-Based Piezoelectric Sensor. *ACS Applied Electronic Materials*, **2022**, 4, 1301-1310	4	4
94	Formation of silicon carbide nanowire on insulator through direct wet oxidation. *Materials Letters*, **2017**, 196, 280-283	3.3	3
93	Piezo-Hall effect and fundamental piezo-Hall coefficients of single crystal n-type 3C-SiC(100) with low carrier concentration. *Applied Physics Letters*, **2017**, 110, 162903	3.4	3
92	Pseudo-Hall Effect in Single Crystal n-Type 3C-SiC(100) Thin Film. *Key Engineering Materials*, **2017**, 733, 3-7	0.4	3
91	Palladium microfiber network as a platform for hydrogen sensing applications. *Journal of Physics and Chemistry of Solids*, **2019**, 131, 50-54	3.9	3
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86	Design and Simulation of Convective Inertial Sensor **2008**,		3
85	Tactile Perception using Micro Force/Moment Sensor Embedded in Soft Fingertip **2006**,		3

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